



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Takashi TANAKA ET AL.

Serial No. 09/970,621

Filed October 5, 2001

: Confirmation No. 1393

: Docket No. 2001_1507A

: Group Art Unit 3723

: Examiner Lee D. Wilson

METHOD FOR SUPPLYING SLURRY
TO POLISHING APPARATUS

ED
11-4-03
ff 6
Election

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED
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ACCOUNT NO. 23-0975

Sir:

This is in response to the Restriction Requirement of October 3, 2003.

Applicants, by their undersigned representative, hereby elect the invention of Group I, i.e. claims 12-21 and 23-30. However, since the subject of the Group II claims has already been considered by the Examiner, it is respectfully submitted that there would be no undue burden on the Examiner to examine the Group II claims along with the Group I claims. Accordingly, it is respectfully requested that the Examiner withdraw the restriction requirement and examine all of the currently pending claims together.

Having made the required election, a full examination on the merits of the elected invention is hereby requested.

Respectfully submitted,

Takashi TANAKA ET AL.

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